



United Technologies Research Center



Presented by

Sameh Dardona

Principle Research Engineer

Nanosensor Manufacturing Workshop

June 13, 2017

Be Curious  SM

United Technologies Business Units



United Technologies Research Center



Berkeley, CA

Established in 2009, focuses on cyber physical systems and embedded intelligence



East Hartford, CT

Founded in 1929, focuses on a broad range of system engineering, thermal, fluid, material, and informational sciences



Cork, Ireland

Established in 2010, focuses on energy, security and aerospace systems



Rome, Italy

Joined UTC in 2012, focuses on model-based design and embedded systems engineering



Shanghai, China

Established in 1997, focuses on integrated buildings, fluid and mechanical systems



Defining the

cutting edge



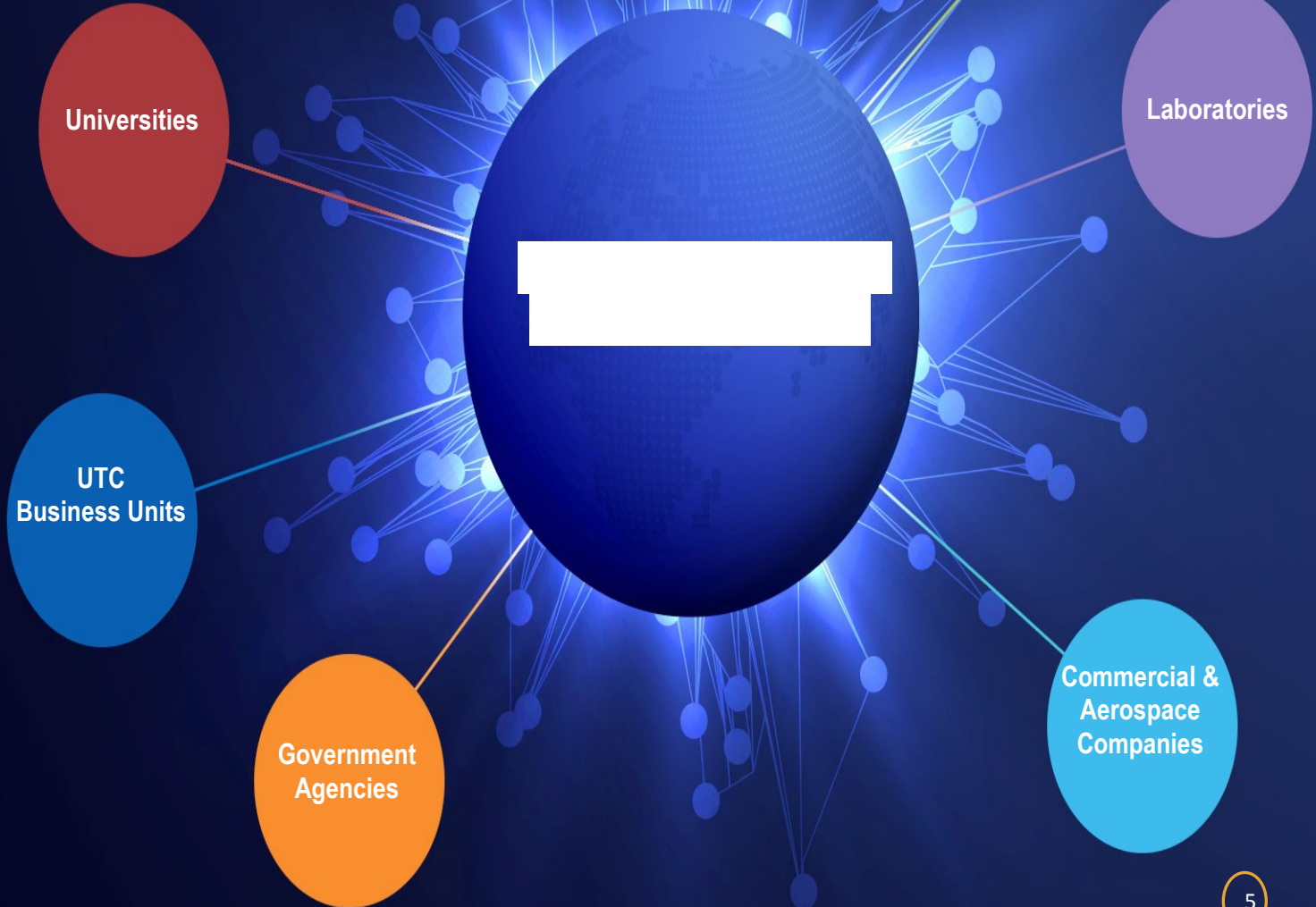
Advanced Manufacturing
Aerodynamics & Acoustics
Applied Mechanics
Autonomy & Controls
Combustion
Cyber Physical Security
Data Science
Embedded Intelligence
Materials
Networks & Communications
Power Electronics
Thermal Management



United Technologies
Research Center



[Redacted]



DIRECT WRITE AND PRINTED ELECTRONICS

Aerospace Systems

Hybrid Manufacturing

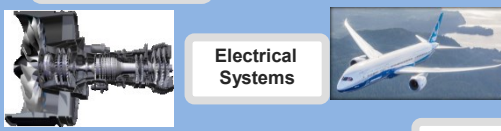
Verification

Electrical Systems

High Temp Sensors

Heaters

Diagnostics & Prognostics




UTC Applications

Embedded Sensors

Lighting - Displays

Environmental Sensors

Functional Packaging



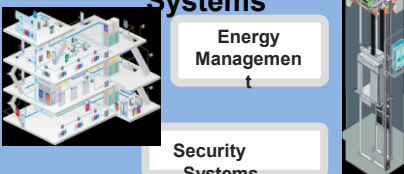
Integrated Building Systems

Energy Management

Security Systems

Control & Positioning

Technician Safety



Delivering Solutions

Functional Components

Electronics



Resistive Heaters

Sensing



Capacitors

Logic & Memory



Photronics

Accelerometers

Communications



Antennas

Actuation



RFID

Piezoelectrics

Touch



Haptics

Energy Harvesting



Photovoltaics

Fuel Cells

Energy Storage



Electrophoretics

Piezoelectrics

Batteries

Lighting



OLEDs

Electroluminescent

Displays



Electrochromics

Liquid crystals

Design for Integrated Structures

Materials & Structures

Additive Manufacturing



Conductors

Metals

Conformal Integration



Semiconductors

3D Assembly



Ceramics

Large Area Components



Polymers

Lamination



Dielectrics

Direct Write Technologies

Dip Pen Nanolithography

Beam Writing & Lithography

Laser-Based

Thermal/Plasma Spray

Ink Jet

Filament-Based

Aerosol Jet

Micro Cold Spray



Roll-to-Roll

DWR2R

Screen

Gravure

Flexo

Slot Die

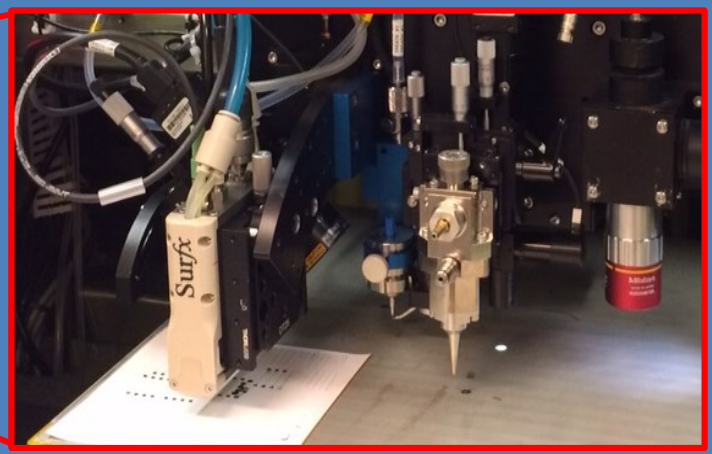
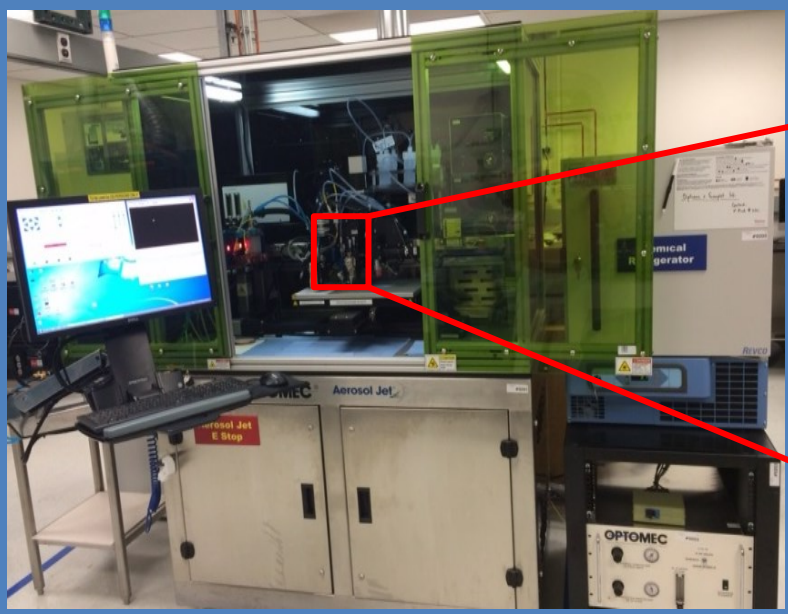


This page does not contain any export controlled technical data

6

Sensors Manufacturing at UTRC

Multi-head Aerosol Jet System by Optomec

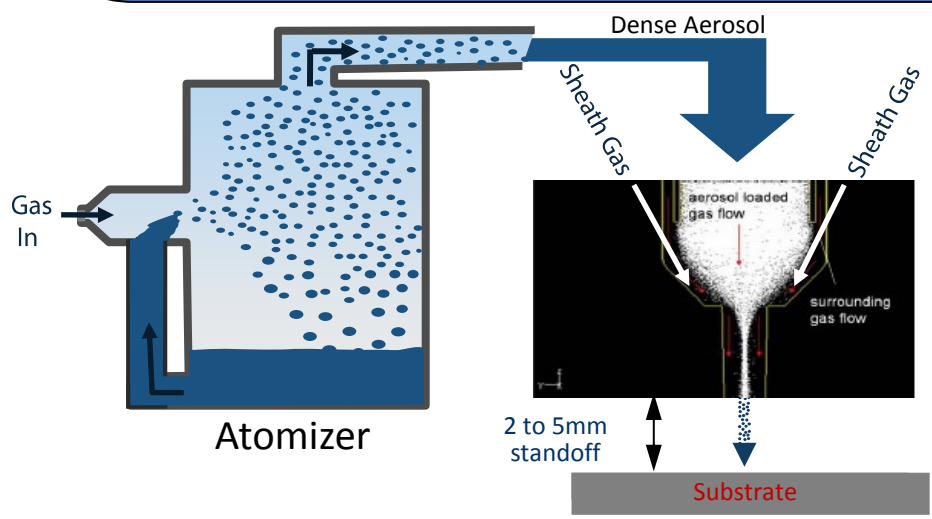


Fine Feature Print Head
(trace width 15µm-300µm)

Laser Cure
(1 W @ 700 nm)

Plasma Head
(Air, N₂, Ar, O₂, H₂, etc.)

Wide Nozzle Print Head
(trace width 0.3-3 mm)



Key benefits

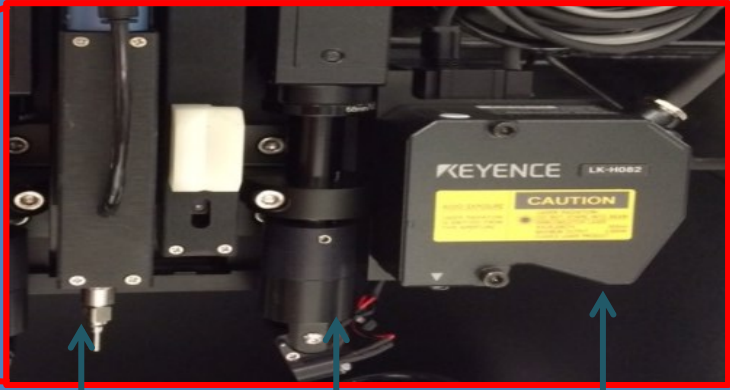
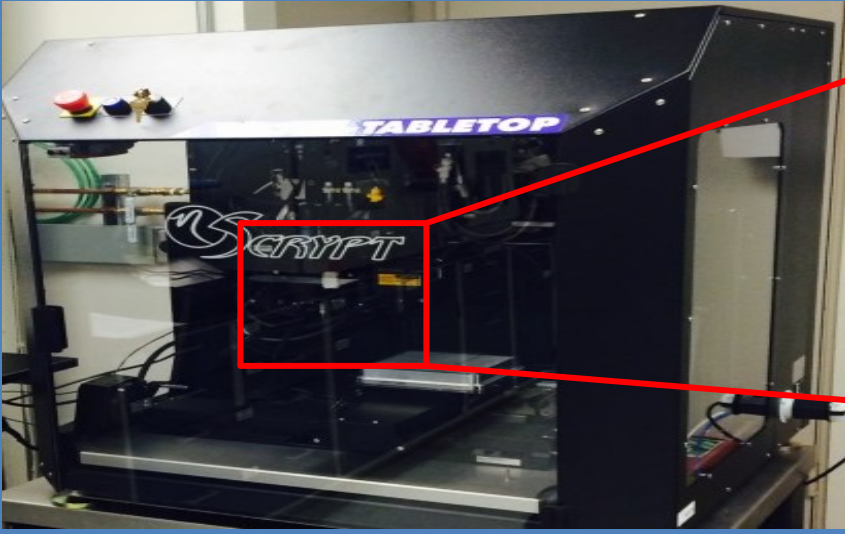
- Widest range of working distances and line widths
- coaxial laser treatment

Key drawbacks

- Complex apparatus
- Requires inks which can be aerosolized

Direct Write Manufacturing of Micro/Nano Sensors

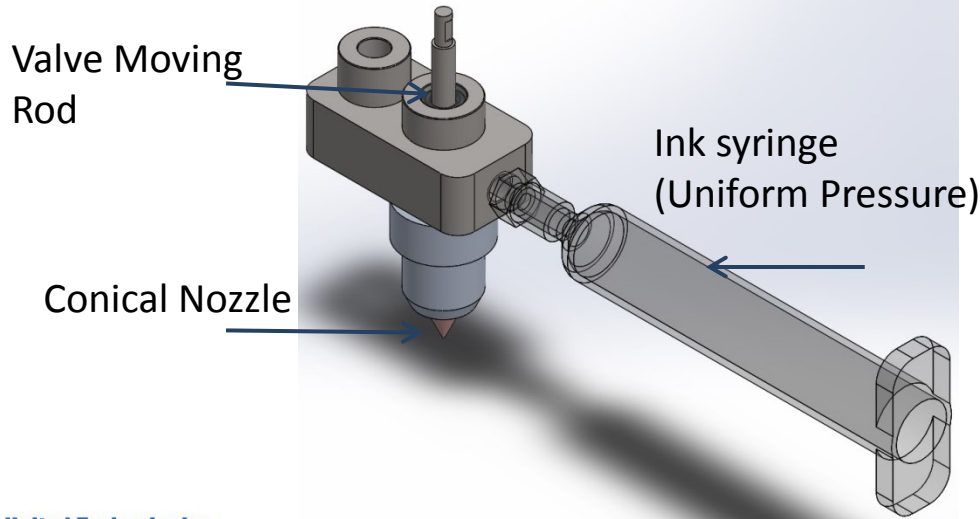
Multi-head Dispensing System by nScript



Pick & Place Tool

Deposition Head

3D Surface Mapping



Key benefits

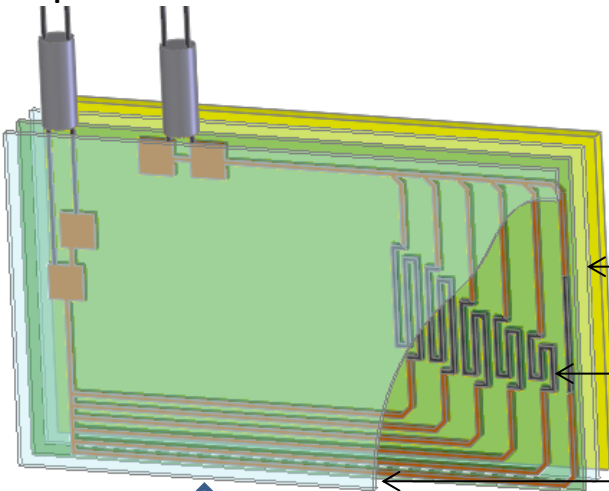
Greatest range of viscosities, simplicity, capable of 3D lattice structures

Key drawbacks

Knowledge of surface topography needed to maintain constant stand-off distance

Wear Sensing Concept

4-probe measurement



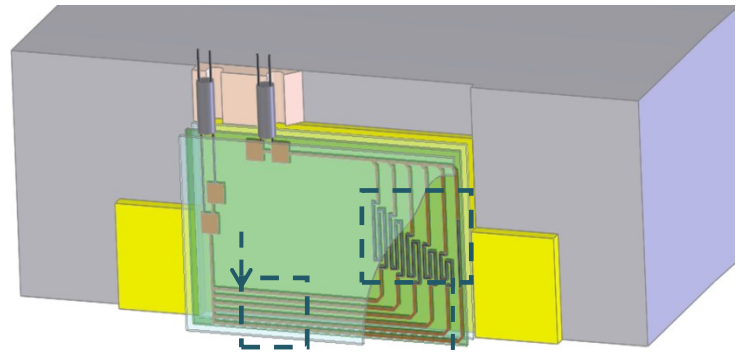
Insulating layer (**printed**)

Device layer (**printed**)

Encapsulating glass layer (**printed**)

Wear Direction

Embedded Wear Sensor



Closely-spaced high conductivity lines

Parallel resistors

Device Circuit Design & Simulation

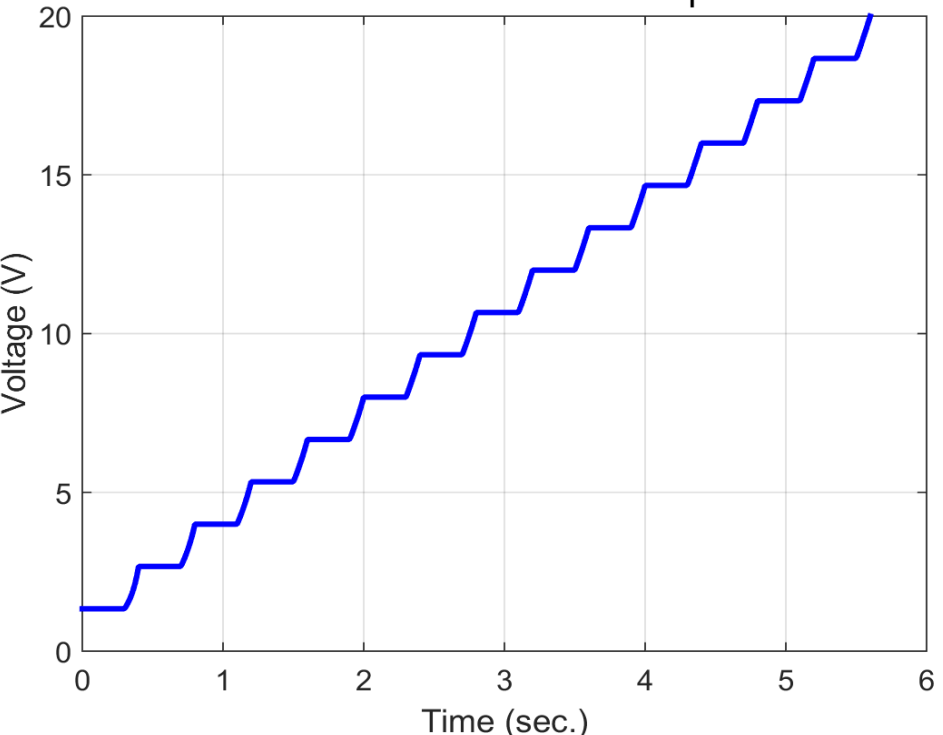
Unequal Value Resistors

- 1) Equal changes in voltage as blade rubs the coating
- 2) Change in voltage is higher than noise level
- 3) Broad range of resistor values needed

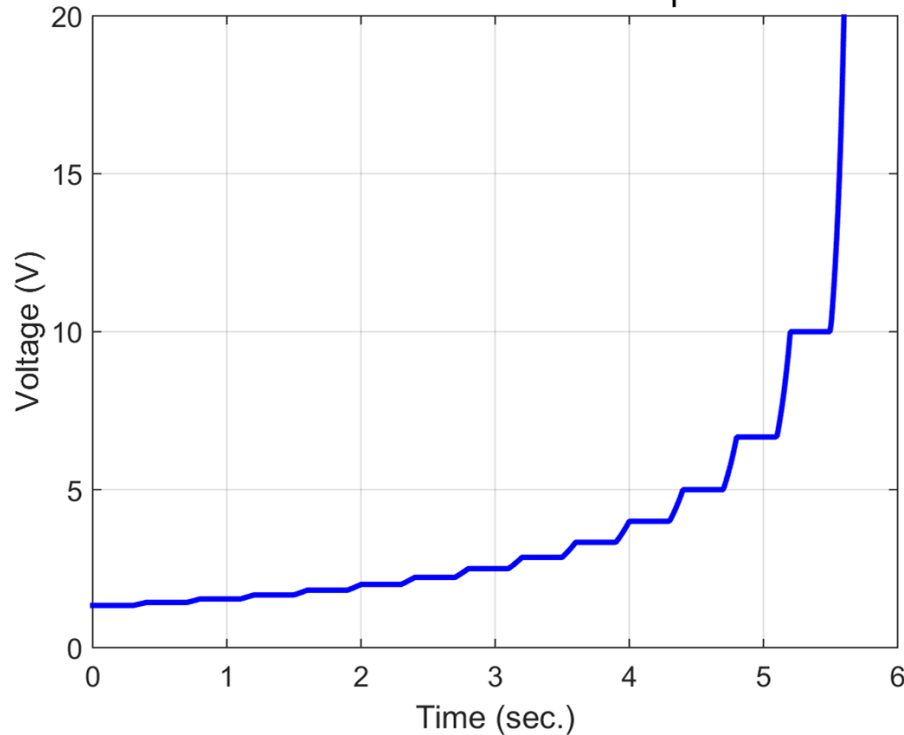
Equal Value Resistors

- 1) Small change in voltage as blade initially rubs the coating
- 2) Some of the voltage changes could be below the noise level during operation (high temperature)

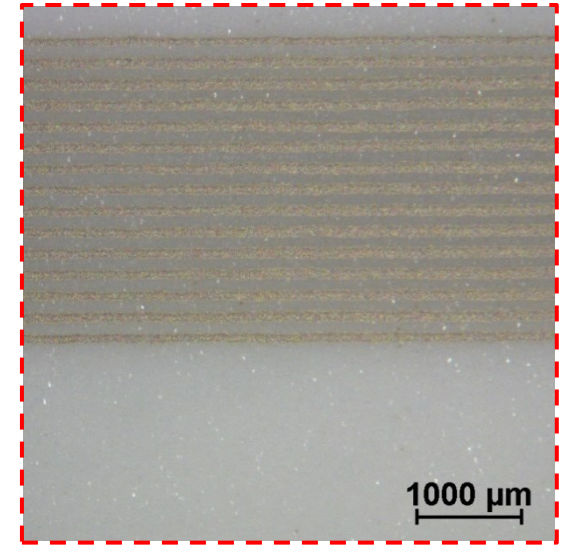
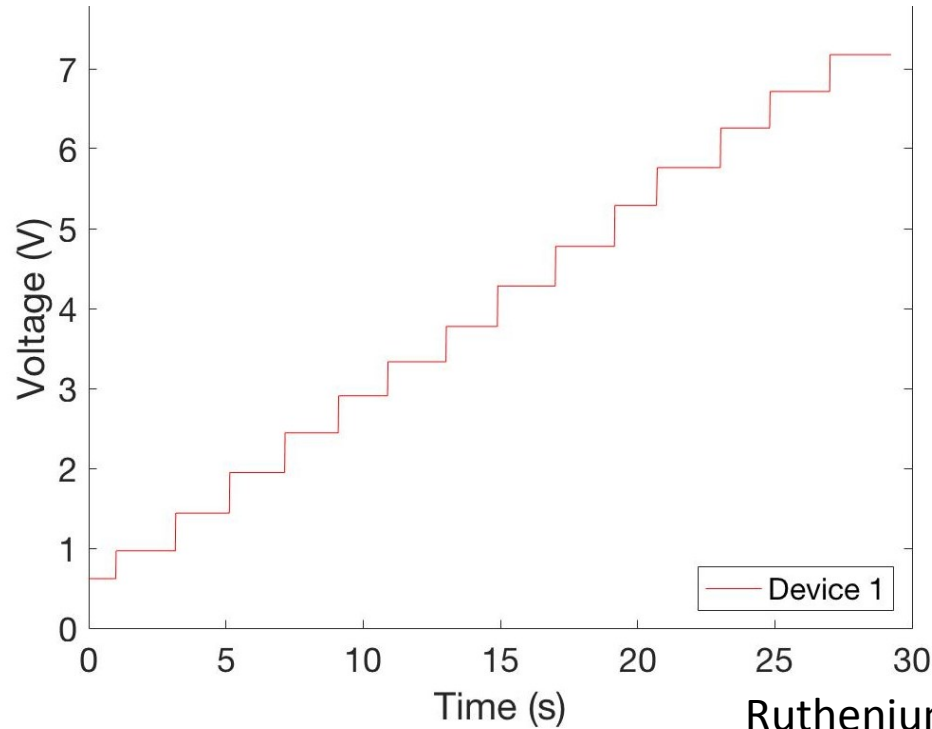
Source I & measure V (I=0.1A, R₁=200Ω)



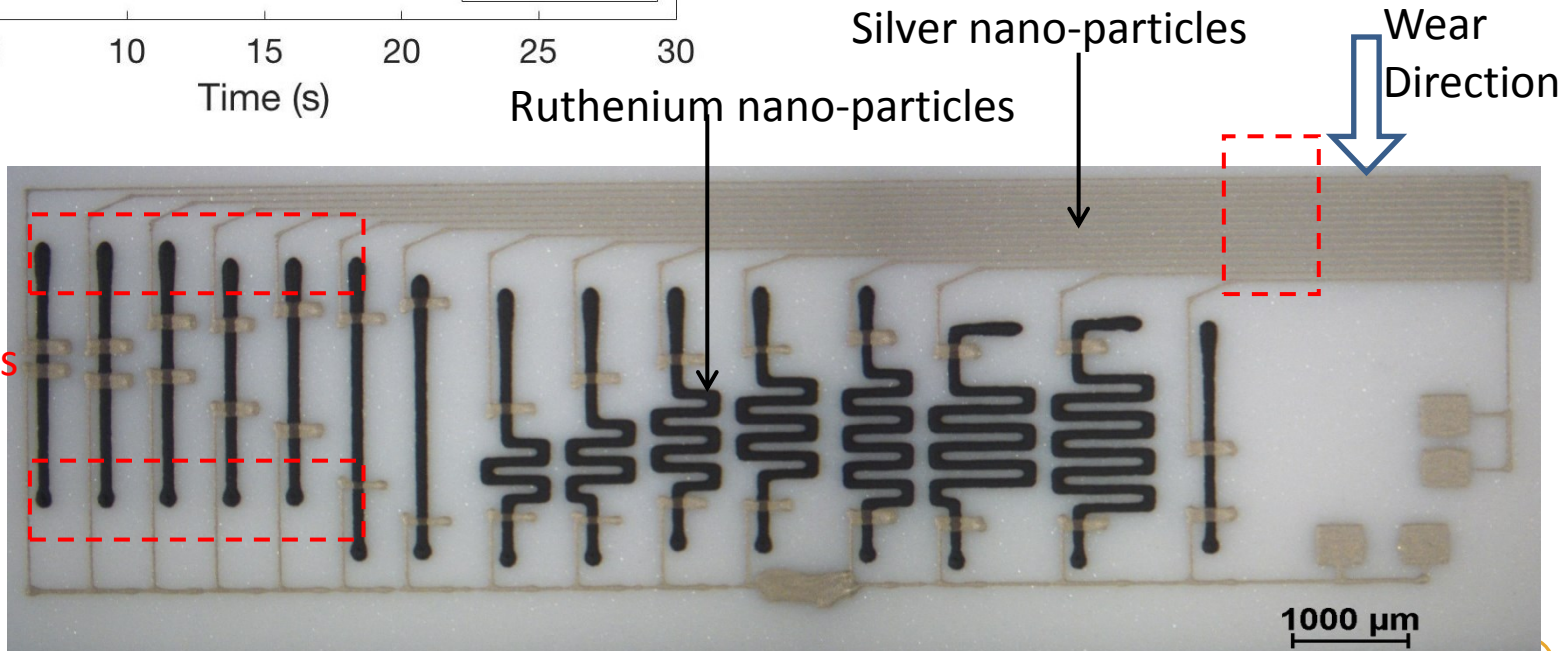
Source I & measure V (I=0.1A, R₁=200Ω)



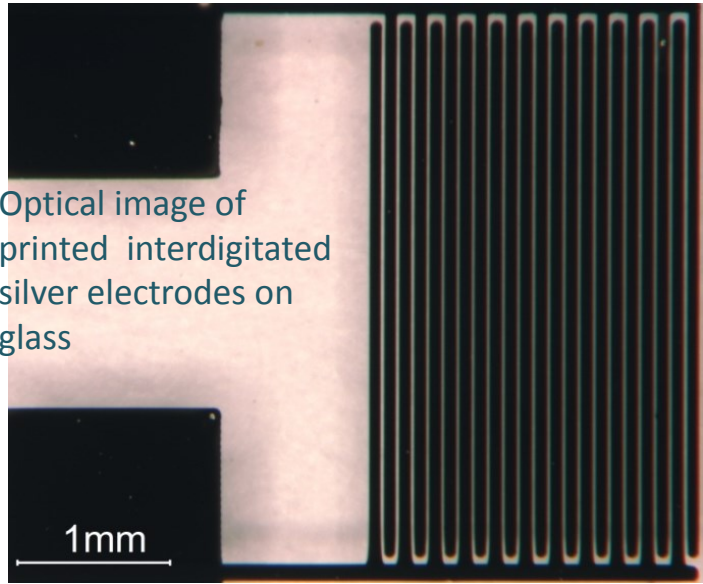
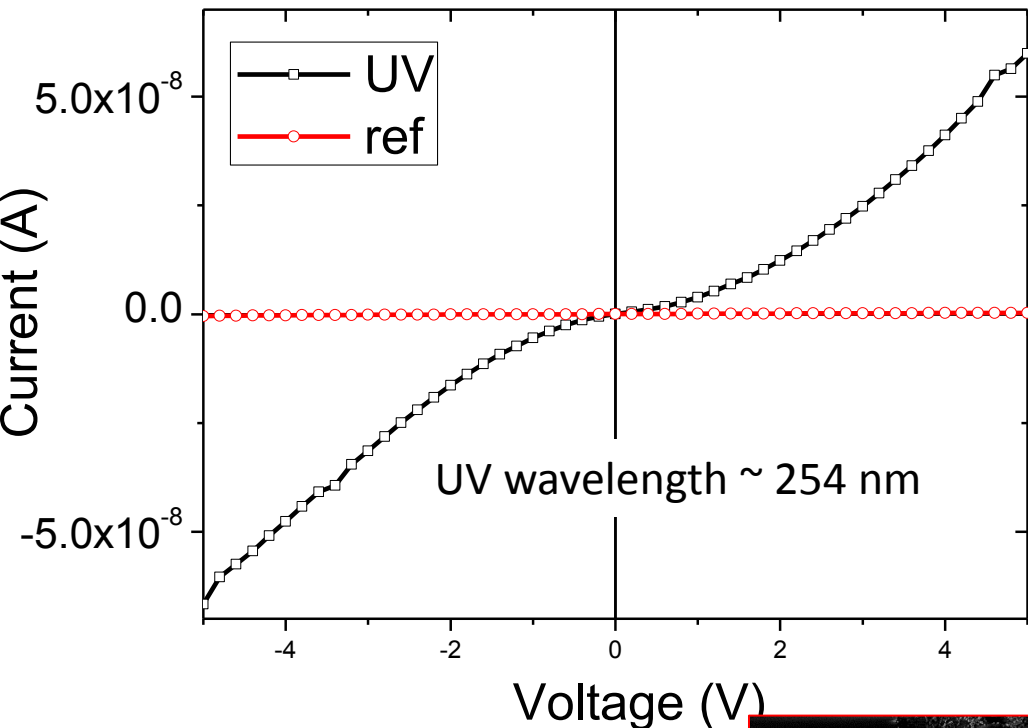
Wear Sensor Design & Manufacturing



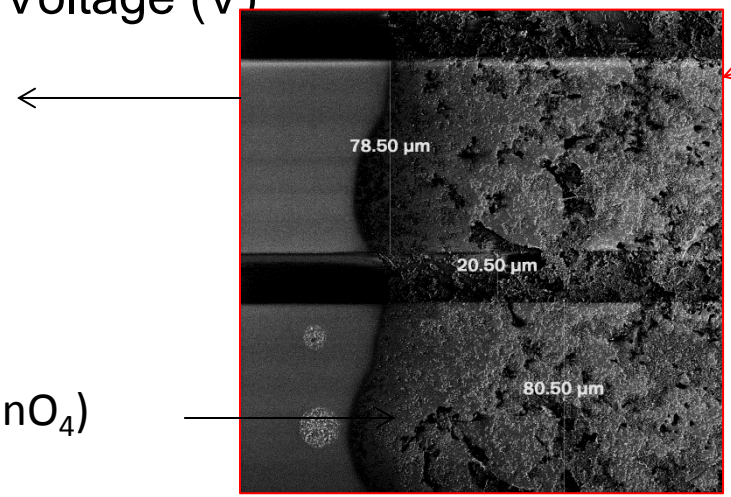
End of lines
create
large variations



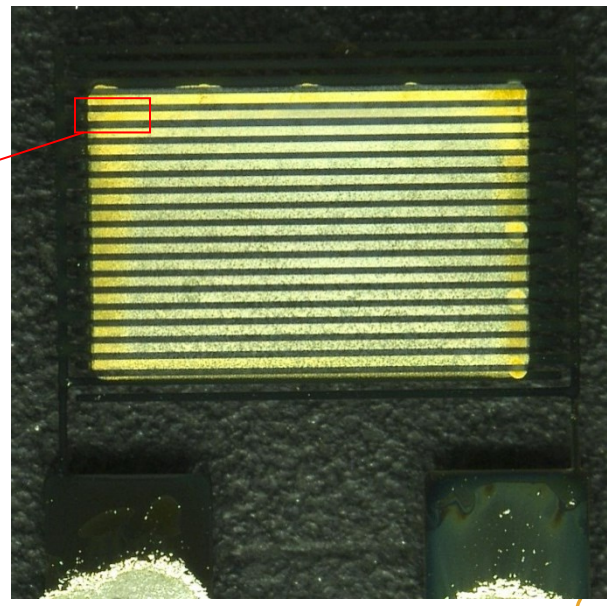
Printed Photoconductive Flame Detector



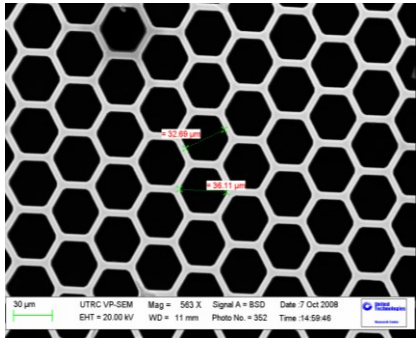
SEM image of all printed Zn_2SnO_3 film and Ag electrodes



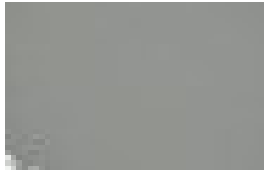
Zinc Tin Oxide Film (Zn_2SnO_4)



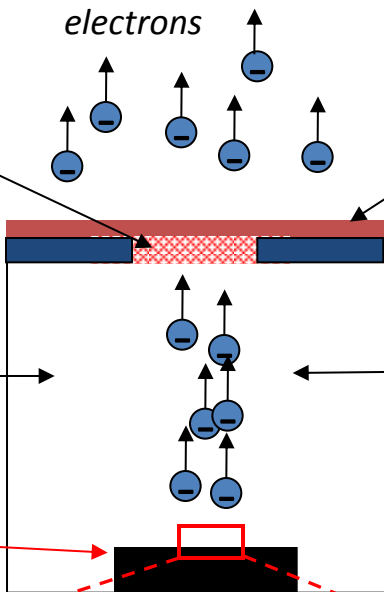
Low Energy Electron Source (non-radioactive)



supporting mesh
(electron anode)



Thin Film of BN/SiN



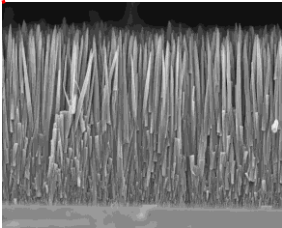
vacuum

electrons

cold cathode

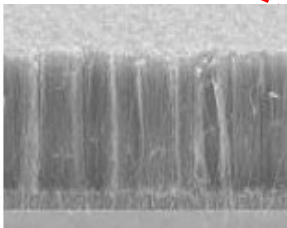
Applications:
 1) Smoke detection
 2) Gas detection

Challenges:
 1) Lifetime of CNTs/ZnO



ZnO needles

OR



Carbon nanotubes

NextFlex Overview

NextFlex is a public-private consortium of companies, academic institutions, nonprofits and governments with a mission to advance US manufacturing of flexible-hybrid electronics.

\$50K membership fee
 \$50K in-kind contribution
 Technical council seat (1 vote)
 Governing council (1/3 vote)

Membership (www.nextflex.us)

CORPORATE

Tier 1

The Boeing Company*

Tier 2

Brewer Science, Inc.*

Eastman Chemical Co*

DuPont

General Electric Company

United Technologies Research Center

Tier 3

Acellent Technologies Inc.*

American Semiconductor, Inc.*

Custom Electronics, Inc.*

E Ink Corporation*

Jabil*

Molex, LLC*

On Semiconductor*

ACADEMIC & NON-PROFIT

Tier 1

Auburn University*

Binghamton University*

Georgia Institute of Technology*

University of Massachusetts Lowell*

University of Texas at Austin*

Tier 2

Purdue University*

University of Arizona*

University of Connecticut*

University of Washington*

Washington State University*

Western Michigan University*

Tier 3

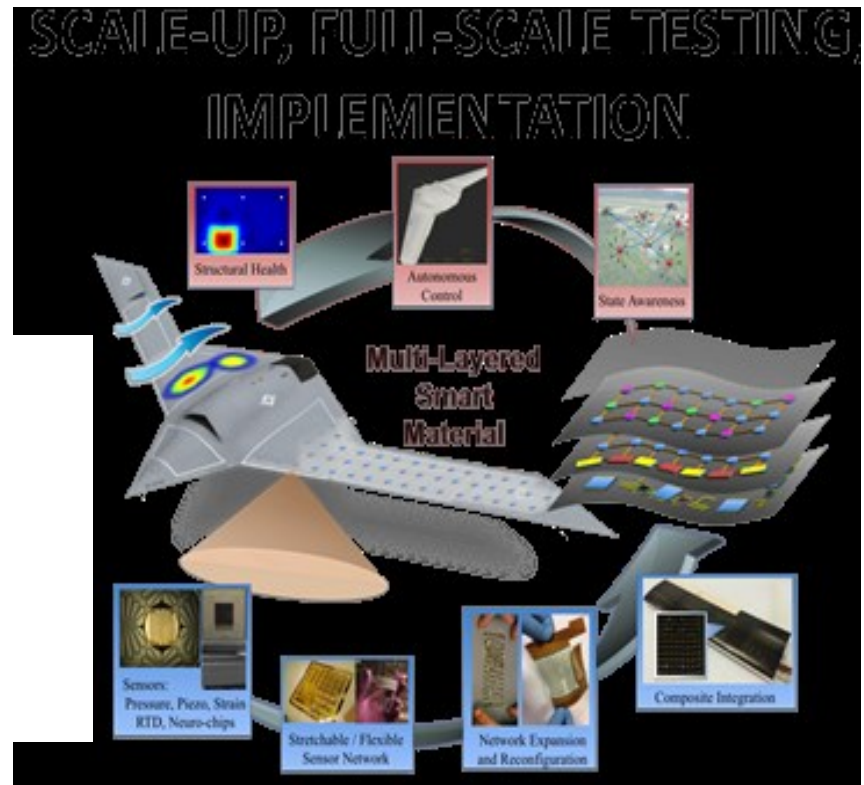
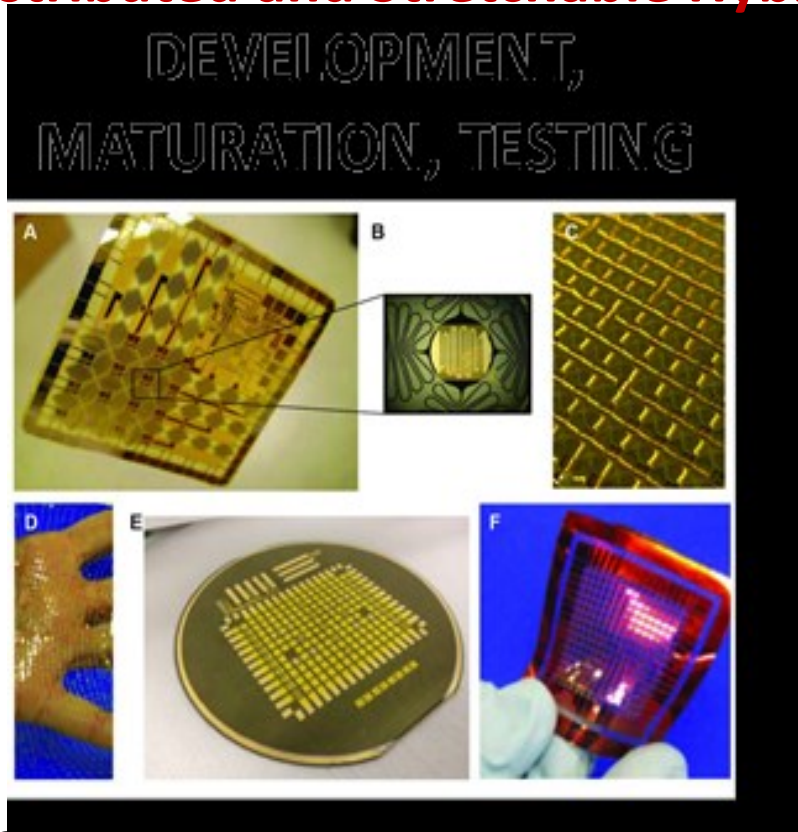
University of Arkansas*

California Polytechnic State University

Proposal Activities

- Project call 1.0 12/2015
- Project call 2.0 04/2016
- Project call 3.0 05/2017

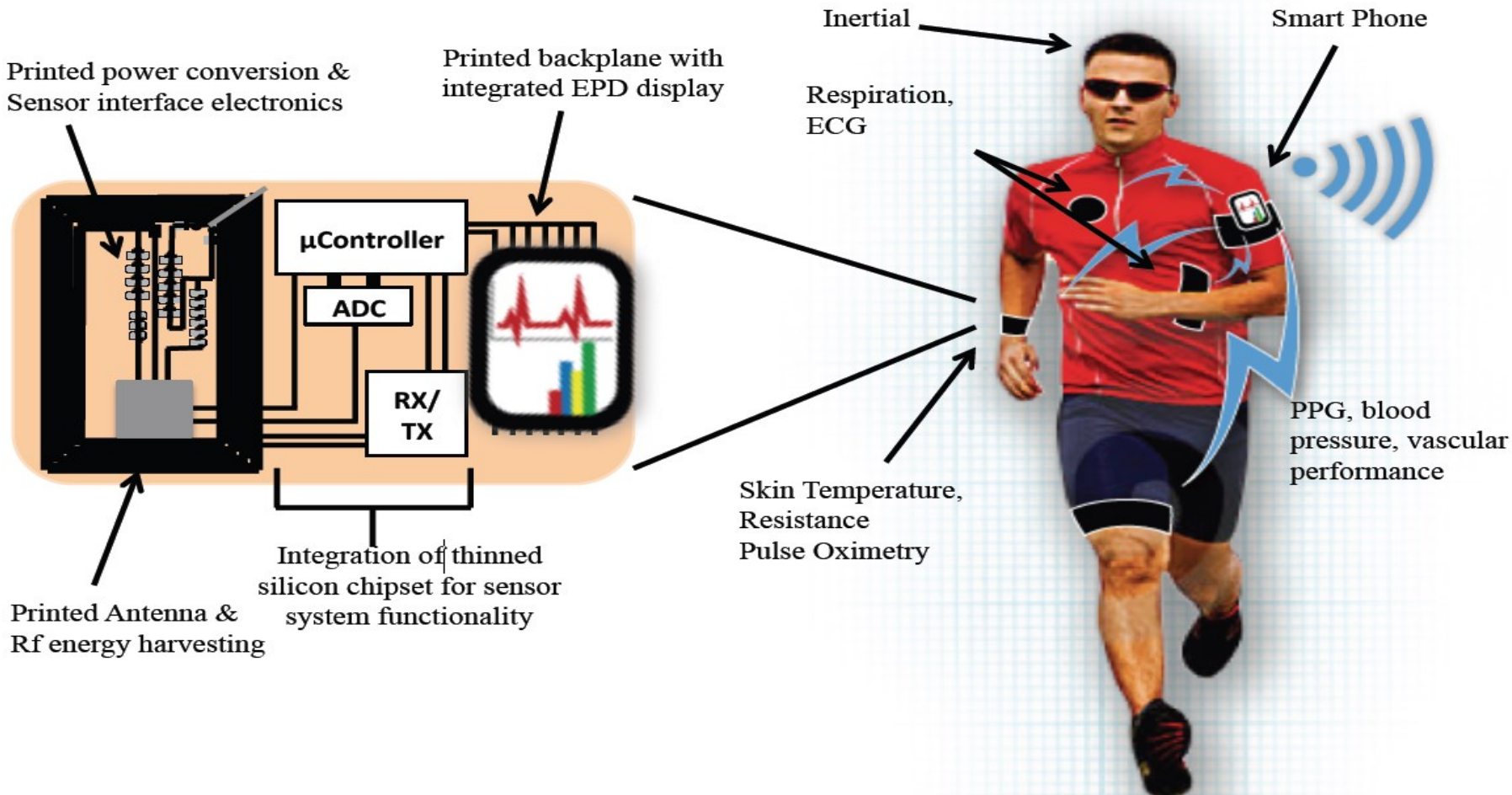
Distributed and Stretchable Hybrid Asset Monitoring Platform



Overall Objectives

- Improve reliability and robustness of sensor nodes and wires using CMOS manufacturing
- Identify and develop pick and place technology
- Tooling for uniform and in-plane stretching and handling of substrates
- Integration and implementation of sensor network qualification tool into manufacturing process
- A demonstrator prototype of value to industry

Scalable Manufacturing for a Wearable, Integrated Human Performance Monitoring System



Demonstrate a Human Performance Monitoring Platform (HPM) consisting of pulse oximeter and heart rate sensors printed on flexible substrates integrated with conductive trace interconnects. Demonstrator includes integrated power management with energy harvesting, low energy Bluetooth (BLE) with printed antenna architecture, and low-power display and display controller electronic sub-systems.

THANK YOU

Sameh Dardona
dardona@utrc.utc.com